

Ola Nilsen

List of Publications by Year in descending order

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147
papers

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94381

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all docs

149
docs citations

149
times ranked

4119
citing authors

#	ARTICLE	IF	CITATIONS
1	Growth of thin films of molybdenum oxide by atomic layer deposition. Journal of Materials Chemistry, 2011, 21, 705-710.	6.7	133
2	All-gas-phase synthesis of UiO-66 through modulated atomic layer deposition. Nature Communications, 2016, 7, 13578.	5.8	129
3	Structural and morphological properties of ZnO:Ga thin films. Thin Solid Films, 2006, 515, 472-476.	0.8	107
4	Growth of manganese oxide thin films by atomic layer deposition. Thin Solid Films, 2003, 444, 44-51.	0.8	101
5	Deposition of thin films of organic-inorganic hybrid materials based on aromatic carboxylic acids by atomic layer deposition. Dalton Transactions, 2010, 39, 11628.	1.6	98
6	Atomic Layer Deposition of $\text{Li}_2\text{O}/\text{Al}_2\text{O}_3$ Thin Films. Chemistry of Materials, 2011, 23, 4669-4675.	3.2	94
7	Growth of thin films of Co_3O_4 by atomic layer deposition. Thin Solid Films, 2007, 515, 7772-7781.	0.8	87
8	Lanthanum titanate and lithium lanthanum titanate thin films grown by atomic layer deposition. Journal of Materials Chemistry, 2010, 20, 2877.	6.7	87
9	Atomic layer deposition of lithium containing thin films. Journal of Materials Chemistry, 2009, 19, 8767.	6.7	81
10	Deposition of Organic- Inorganic Hybrid Materials by Atomic Layer Deposition. ECS Transactions, 2008, 16, 3-14.	0.3	77
11	Growth of Nano-Needles of Manganese(IV) Oxide by Atomic Layer Deposition. Journal of Nanoscience and Nanotechnology, 2008, 8, 1003-1011.	0.9	75
12	Atomic Layer Deposition of Spinel Lithium Manganese Oxide by Film-Body-Controlled Lithium Incorporation for Thin-Film Lithium-Ion Batteries. Journal of Physical Chemistry C, 2014, 118, 1258-1268.	1.5	66
13	Atomic layer deposition of organic-inorganic hybrid materials based on saturated linear carboxylic acids. Dalton Transactions, 2011, 40, 4636.	1.6	65
14	Growth of calcium carbonate by the atomic layer chemical vapour deposition technique. Thin Solid Films, 2004, 450, 240-247.	0.8	55
15	Sensors for optical thermometry based on luminescence from layered $\text{YVO}_4: \text{Ln}^{3+}$ ($\text{Ln} = \text{Nd, Sm, Eu, Dy}$). Tj ETQq1 1_0.784314	1.6	55
16	Atomic layer deposition of ferroelectric LiNbO_3 . Journal of Materials Chemistry C, 2013, 1, 4283-4290.	2.7	54
17	High power nano-structured V_2O_5 thin film cathodes by atomic layer deposition. Journal of Materials Chemistry A, 2014, 2, 15044-15051.	5.2	52
18	Effect of magnetic field on the growth of Fe_2O_3 thin films by atomic layer deposition. Applied Surface Science, 2004, 227, 40-47.	3.1	51

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19	Thin films of In ₂ O ₃ by atomic layer deposition using In(acac) ₃ . Thin Solid Films, 2009, 517, 6320-6322.	0.8	51
20	Combination of characterization techniques for atomic layer deposition MoO ₃ coatings: From the amorphous to the orthorhombic \pm -MoO ₃ crystalline phase. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2012, 30, .	0.9	51
21	Atomic layer deposition of functional films for Li-ion microbatteries. Physica Status Solidi (A) Applications and Materials Science, 2014, 211, 357-367.	0.8	51
22	Functional Perovskites by Atomic Layer Deposition – An Overview. Advanced Materials Interfaces, 2017, 4, 1600903.	1.9	51
23	Growth of La _{1-x} CaxMnO ₃ thin films by atomic layer deposition. Journal of Materials Chemistry, 2007, 17, 1466-1475.	6.7	50
24	Epitaxial growth of cobalt oxide by atomic layer deposition. Journal of Crystal Growth, 2007, 307, 457-465.	0.7	50
25	High-performing iron phosphate for enhanced lithium ion solid state batteries as grown by atomic layer deposition. Journal of Materials Chemistry A, 2013, 1, 9054-9059.	5.2	49
26	Atomic layer deposition of Li _x Ti _y O _z thin films. RSC Advances, 2013, 3, 7537-7542.	1.7	49
27	Analytical model for island growth in atomic layer deposition using geometrical principles. Journal of Applied Physics, 2007, 102, 024906.	1.1	47
28	Thin Films of Cobalt Oxide Deposited on High Aspect Ratio Supports by Atomic Layer Deposition. Chemical Vapor Deposition, 2011, 17, 135-140.	1.4	47
29	Effect of substrate on the characteristics of manganese(IV) oxide thin films prepared by atomic layer deposition. Thin Solid Films, 2004, 468, 65-74.	0.8	46
30	Effect of heat treatment on ITO film properties and ITO/p-Si interface. Materials Chemistry and Physics, 2009, 114, 425-429.	2.0	45
31	Novel materials by atomic layer deposition and molecular layer deposition. MRS Bulletin, 2011, 36, 877-884.	1.7	45
32	All-gas-phase synthesis of amino-functionalized UiO-66 thin films. Dalton Transactions, 2017, 46, 16983-16992.	1.6	45
33	Atomic layer deposition of lithium nitride and carbonate using lithium silylamide. RSC Advances, 2012, 2, 6315.	1.7	42
34	MOF thin films with bi-aromatic linkers grown by molecular layer deposition. Journal of Materials Chemistry A, 2020, 8, 2539-2548.	5.2	42
35	Electrical properties of Al ₂ O ₃ -SiC structures grown by atomic layer chemical vapor deposition. Journal of Applied Physics, 2007, 102, 054513.	1.1	41
36	Black silicon with order-disordered structures for enhanced light trapping and photothermal conversion. Nano Energy, 2019, 65, 103992.	8.2	41

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37	Surface Forces Apparatus Measurements of Interactions between Rough and Reactive Calcite Surfaces. <i>Langmuir</i> , 2018, 34, 7248-7263.	1.6	39
38	Thin film deposition of lanthanum manganite perovskite by the ALE process. <i>Journal of Materials Chemistry</i> , 1999, 9, 1781-1784.	6.7	38
39	The 1.54- μm photoluminescence from an (Er, Ge) co-doped SiO ₂ film deposited on Si by rf magnetron sputtering. <i>Applied Physics Letters</i> , 2004, 85, 4475.	1.5	36
40	Structural and optical properties of lanthanide oxides grown by atomic layer deposition (Ln = Pr, Nd). <i>Tj ETQq0 0 0 rBT /Overlock 10 Tf</i>	1.6	34
41	Electrical characterization of amorphous LiAlO ₂ thin films deposited by atomic layer deposition. <i>RSC Advances</i> , 2016, 6, 60479-60486.	1.7	34
42	Simulation of growth dynamics in atomic layer deposition. Part I. Amorphous films. <i>Thin Solid Films</i> , 2007, 515, 4527-4537.	0.8	32
43	Reconstruction of platinum-rhodium catalysts during oxidation of ammonia. <i>Applied Catalysis A: General</i> , 2005, 284, 163-176.	2.2	31
44	Simulation of growth dynamics in atomic layer deposition. Part II. Polycrystalline films from cubic crystallites. <i>Thin Solid Films</i> , 2007, 515, 4538-4549.	0.8	31
45	The work function of n-ZnO deduced from heterojunctions with Si prepared by ALD. <i>Journal Physics D: Applied Physics</i> , 2012, 45, 315101.	1.3	31
46	Enhanced Osteoblast Differentiation on Scaffolds Coated with TiO ₂ Compared to SiO ₂ and CaP Coatings. <i>Biointerphases</i> , 2012, 7, 36.	0.6	29
47	Optical Properties of Vanadium Pentoxide Deposited by ALD. <i>Journal of Physical Chemistry C</i> , 2012, 116, 19444-19450.	1.5	29
48	Structural, electrical and optical characterization of Ti-doped ZnO films grown by atomic layer deposition. <i>Journal of Alloys and Compounds</i> , 2014, 616, 618-624.	2.8	29
49	Atomic Layer Deposition of Organic-Inorganic Hybrid Materials Based on Unsaturated Linear Carboxylic Acids. <i>European Journal of Inorganic Chemistry</i> , 2011, 2011, 5305-5312.	1.0	28
50	Atomic Layer Deposition of Copper Oxide using Copper(II) Acetylacetonate and Ozone. <i>Chemical Vapor Deposition</i> , 2012, 18, 173-178.	1.4	27
51	Atomic layer deposition of (K,Na)(Nb,Ta)O ₃ thin films. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2016, 34, .	0.9	27
52	Growth of iron cobalt oxides by atomic layer deposition. <i>Dalton Transactions</i> , 2008, , 253-259.	1.6	26
53	Comparison of near-interface traps in Al ₂ O ₃ ·4H-SiC and Al ₂ O ₃ ·SiO ₂ ·4H-SiC structures. <i>Applied Physics Letters</i> , 2006, 89, 222103.	1.5	25
54	Growth of La _{1-x} Sr _x FeO ₃ thin films by atomic layer deposition. <i>Dalton Transactions</i> , 2009, , 481-489.	1.6	25

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55	A foundation for complex oxide electronics -low temperature perovskite epitaxy. Nature Communications, 2020, 11, 2872.	5.8	24
56	Reconstruction and loss of platinum catalyst during oxidation of ammonia. Applied Catalysis A: General, 2001, 207, 43-54.	2.2	23
57	Effect of ZrO ₂ addition on the mechanical properties of porous TiO ₂ bone scaffolds. Materials Science and Engineering C, 2012, 32, 1386-1393.	3.8	21
58	Neutron diffraction and Raman analysis of LiMn _{1.5} Ni _{0.5} O ₄ spinel type oxides for use as lithium ion battery cathode and their capacity enhancements. Solid State Ionics, 2016, 284, 28-36.	1.3	21
59	Simulation of growth dynamics in atomic layer deposition. Part III. Polycrystalline films from tetragonal crystallites. Thin Solid Films, 2007, 515, 4550-4558.	0.8	20
60	(Invited) Reaction Mechanisms in ALD of Ternary Oxides. ECS Transactions, 2011, 41, 175-183.	0.3	20
61	Chemical vapor transport of platinum and rhodium with oxygen as transport agent. Journal of Crystal Growth, 2005, 279, 206-212.	0.7	19
62	An iron(II) diketonate-diamine complex as precursor for thin film fabrication by atomic layer deposition. Applied Surface Science, 2015, 347, 861-867.	3.1	19
63	Crystallization, Phase Stability, and Electrochemical Performance of Hf-MoO_3 Thin Films. Crystal Growth and Design, 2020, 20, 3861-3866.	1.4	19
64	The effect of fluoride surface modification of ceramic TiO ₂ on the surface properties and biological response of osteoblastic cells <i>in vitro</i> . Biomedical Materials (Bristol), 2011, 6, 045006.	1.7	17
65	Atomic layer deposited lithium aluminum oxide: (In)dependency of film properties from pulsing sequence. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2015, 33, .	0.9	17
66	In situ synchrotron study of ordered and disordered LiMn _{1.5} Ni _{0.5} O ₄ as lithium ion battery positive electrode. Acta Materialia, 2016, 116, 290-297.	3.8	17
67	Inexpensive set-up for determination of decomposition temperature for volatile compounds. Thermochimica Acta, 2003, 404, 187-192.	1.2	16
68	Oxide Coating of Alumina Nanoporous Structure Using ALD to Produce Highly Porous Spinel. Chemical Vapor Deposition, 2012, 18, 315-325.	1.4	16
69	Influence of precursors chemistry on ALD growth of cobalt-molybdenum oxide films. Dalton Transactions, 2012, 41, 2439.	1.6	15
70	Atomic Layer Deposition of LaPO ₄ and Ca:LaPO ₄ ** ^{††} . Chemical Vapor Deposition, 2014, 20, 269-273.	1.4	15
71	Thickness dependent structural, optical and electrical properties of Ti-doped ZnO films prepared by atomic layer deposition. Applied Surface Science, 2015, 332, 494-499.	3.1	15
72	<i>tert</i> -butoxides as precursors for atomic layer deposition of alkali metal containing thin films. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2020, 38, .	0.9	15

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73	Intense NIR emission in $\text{YVO}_4:\text{Yb}^{3+}$ thin films by atomic layer deposition. <i>Journal of Materials Chemistry C</i> , 2017, 5, 8572-8578.	2.7	14
74	Surface reconstruction on noble-metal catalysts during oxidation of ammonia. <i>Applied Catalysis A: General</i> , 2005, 284, 185-192.	2.2	13
75	Rearrangement of the oxide-semiconductor interface in annealed $\text{Al}_2\text{O}_3/\text{4H-SiC}$ structures. <i>Applied Physics Letters</i> , 2007, 91, 052907.	1.5	13
76	Luminescent Properties of Multilayered Eu_2O_3 and TiO_2 Grown by Atomic Layer Deposition**. <i>Chemical Vapor Deposition</i> , 2014, 20, 274-281.	1.4	13
77	Ultra-high power capabilities in amorphous FePO_4 thin films. <i>Journal of Power Sources</i> , 2016, 306, 454-458.	4.0	13
78	Phase Control in Thin Films of Layered Cuprates. <i>Chemistry of Materials</i> , 2018, 30, 1095-1101.	3.2	13
79	Simulation of growth dynamics for nearly epitaxial films. <i>Journal of Crystal Growth</i> , 2007, 308, 366-375.	0.7	12
80	Luminescent properties of europium titanium phosphate thin films deposited by atomic layer deposition. <i>RSC Advances</i> , 2017, 7, 8051-8059.	1.7	12
81	Molecular Hybrid Structures by Atomic Layer Deposition – Deposition of Al_3 , Zn_2 and Ti_4 ($q = \text{hydroxyquinoline}$). <i>Chemical Vapor Deposition</i> , 2013, 19, 4 174-179.		11
82	Luminescence properties of europium titanate thin films grown by atomic layer deposition. <i>RSC Advances</i> , 2014, 4, 11876-11883.	1.7	11
83	Atomic Layer Deposition of oriented nickel titanate (NiTiO_3). <i>Applied Surface Science</i> , 2014, 311, 478-483.	3.1	11
84	Luminescence properties of lanthanide and ytterbium lanthanide titanate thin films grown by atomic layer deposition. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2016, 34, .	0.9	11
85	Enhanced process and composition control for atomic layer deposition with lithium trimethylsilanolate. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2017, 35, .	0.9	11
86	Molecular layer deposition builds biocompatible substrates for epithelial cells. <i>Journal of Biomedical Materials Research - Part A</i> , 2018, 106, 3090-3098.	2.1	11
87	Chemical Uniformity in Ferroelectric $\text{K} \times \text{Na} \text{ } \times \text{NbO}_3$ Thin Films. <i>Global Challenges</i> , 2019, 3, 1800114.	1.8	11
88	ALD Applied to Conformal Coating of Nanoporous $\text{ }^3\text{-Alumina}$: Spinel Formation and Luminescence Induced by Europium Doping. <i>Journal of the Electrochemical Society</i> , 2012, 159, P45-P49.	1.3	10
89	Thin film fabrication and characterization of proton conducting lanthanum tungstate. <i>Journal of Materials Chemistry A</i> , 2014, 2, 18463-18471.	5.2	10
90	Luminescent YbVO_4 by atomic layer deposition. <i>Dalton Transactions</i> , 2017, 46, 3008-3013.	1.6	10

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91	Rubidium containing thin films by atomic layer deposition. Dalton Transactions, 2017, 46, 16139-16144.	1.6	10
92	Utilizing Zirconium MOF-functionalized Fiber Substrates Prepared by Molecular Layer Deposition for Toxic Gas Capture and Chemical Warfare Agent Degradation. Global Challenges, 2021, 5, 2100001.	1.8	10
93	Effect of γ -Fe ₂ O ₃ surface coating on reconstruction of platinum-rhodium catalysts during oxidation of ammonia. Applied Catalysis A: General, 2005, 284, 177-184.	2.2	9
94	Interfacial studies of Al ₂ O ₃ deposited on 4H-SiC(0001). Surface and Interface Analysis, 2008, 40, 822-825.	0.8	9
95	(Invited) ALD of Thin Films for Lithium-Ion Batteries. ECS Transactions, 2011, 41, 331-339.	0.3	9
96	Deposition and x-ray characterization of epitaxial thin films of LaAlO ₃ . Thin Solid Films, 2014, 550, 90-94.	0.8	9
97	Atomic layer deposited TiO ₂ protects porous ceramic foams from grain boundary corrosion. Corrosion Science, 2016, 106, 35-42.	3.0	9
98	Biocompatible organic-inorganic hybrid materials based on nucleobases and titanium developed by molecular layer deposition. Beilstein Journal of Nanotechnology, 2019, 10, 399-411.	1.5	9
99	Electrical Properties of Aluminium Oxide Films Grown by Atomic Layer Deposition on n-Type 4H-SiC. Materials Science Forum, 2005, 483-485, 705-708.	0.3	8
100	High Temperature Annealing Study of Al ₂ O ₃ Deposited by ALCVD on n-Type 4H-SiC. Materials Science Forum, 2006, 527-529, 1067-1070.	0.3	8
101	ALD Applied to Conformal Coating of Nanoporous γ -Alumina: Spinel Formation and Luminescence Induced by Europium Doping. ECS Transactions, 2011, 41, 123-130.	0.3	8
102	Measuring the heat evolved from individual reaction steps in atomic layer deposition. Journal of Thermal Analysis and Calorimetry, 2011, 105, 33-37.	2.0	8
103	Controlling luminescence and quenching mechanisms in subnanometer multilayer structure of europium titanium oxide thin films. Journal of Luminescence, 2019, 215, 116618.	1.5	8
104	Molecular layer deposition of photoactive metal-naphthalene hybrid thin films. Dalton Transactions, 2021, 50, 12896-12905.	1.6	8
105	Etching of platinum-rhodium alloys in oxygen-containing atmospheres. Journal of Alloys and Compounds, 2005, 402, 53-57.	2.8	7
106	Electronic Properties of ZnO/Si Heterojunction Prepared by ALD.. Solid State Phenomena, 0, 178-179, 130-135.	0.3	7
107	The γ and δ plasma modes in plasma-enhanced atomic layer deposition with O ₂ -N ₂ capacitive discharges. Journal Physics D: Applied Physics, 2017, 50, 095201.	1.3	7
108	Control of growth orientation in as-deposited epitaxial iron-rich nickel ferrite spinel. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2019, 37, 021502.	0.9	7

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109	Single-step approach to sensitized luminescence through bulk-embedded organics in crystalline fluorides. <i>Communications Chemistry</i> , 2020, 3, .	2.0	7
110	Area-selective atomic layer deposition of molybdenum oxide. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2020, 38, .	0.9	7
111	Title is missing!. <i>Oxidation of Metals</i> , 2003, 59, 215-232.	1.0	6
112	Ionic conductivity in Li_xTaO_y thin films grown by atomic layer deposition. <i>Electrochimica Acta</i> , 2020, 361, 137019.	2.6	6
113	Tuning electronic properties in LaNiO_3 thin films by B-site Cu-substitution. <i>Journal of Materials Chemistry C</i> , 2020, 8, 12662-12668.	2.7	6
114	Atomic Layer Deposition of GdCoO_3 and $\text{Gd}_{0.9}\text{Ca}_{0.1}\text{CoO}_3$. <i>Materials</i> , 2020, 13, 24.	1.3	6
115	On the application of a single-crystal $\hat{\rho}$ -diffractometer and a CCD area detector for $\hat{\text{A}}$ studies of thin films. <i>Journal of Synchrotron Radiation</i> , 2013, 20, 644-647.	1.0	5
116	LiF by atomic layer deposition $\hat{\text{e}}$ "Made easy. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2020, 38, .	0.9	5
117	Understanding KO^{t} Bu in atomic layer deposition $\hat{\text{e}}$ " <i>in situ</i> mechanistic studies of the KNbO_3 growth process. <i>Dalton Transactions</i> , 2020, 49, 13233-13242.	1.6	5
118	Solar-driven plasmonic heterostructure $\text{Ti/TiO}_2^{\text{x}}$ with gradient doping for sustainable plasmon-enhanced catalysis. <i>Physical Chemistry Chemical Physics</i> , 2020, 22, 7769-7777.	1.3	5
119	Structure determination of MnO_2 films grown on single crystal $\hat{\pm}$ - Al_2O_3 substrates. <i>Philosophical Magazine</i> , 2005, 85, 2689-2705.	0.7	4
120	Annealing study of H_2O and O_3 grown Al_2O_3 deposited by atomic layer chemical vapour deposition on n-type 4H-SiC. <i>Physica Scripta</i> , 2006, T126, 6-9.	1.2	4
121	X-Ray and AFM Analysis of Al_2O_3 Deposited by ALCVD on n-Type 4H-SiC. <i>Materials Science Forum</i> , 2007, 556-557, 683-686.	0.3	4
122	First complex oxide superconductor by atomic layer deposition. <i>Chemical Communications</i> , 2018, 54, 8253-8256.	2.2	4
123	Phase and Orientation Control of NiTiO_3 Thin Films. <i>Materials</i> , 2020, 13, 112.	1.3	4
124	High power iron phosphate cathodes by atomic layer deposition. <i>Solid State Ionics</i> , 2020, 353, 115377.	1.3	4
125	Effect of Subcycle Arrangement on Direct Epitaxy in ALD of LaNiO_3 . <i>ACS Applied Electronic Materials</i> , 2021, 3, 292-298.	2.0	4
126	Aromatic sensitizers in luminescent hybrid films. <i>RSC Advances</i> , 2022, 12, 18063-18071.	1.7	4

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127	Al incorporation during metal organic chemical vapour deposition of aluminium zinc oxide. Thin Solid Films, 2020, 709, 138245.	0.8	3
128	Quinizarin: a large aromatic molecule well suited for atomic layer deposition. Dalton Transactions, 2021, 50, 8307-8313.	1.6	3
129	Growth of Oxides with Complex Stoichiometry by the ALD Technique, Exemplified by Growth of $\text{La}_{1-x}\text{Ca}_x\text{MnO}_3$. , 0, , 87-100.		2
130	The $\text{Al}_2\text{O}_3/\text{4H-SiC}$ Interface Investigated by Thermal Dielectric Relaxation Current Technique. Materials Science Forum, 2007, 556-557, 537-540.	0.3	2
131	Electrical Properties and Gas Sensing Characteristics of the $\text{Al}_2\text{O}_3/\text{4H-SiC}$ Interface Studied by Impedance Spectroscopy. Materials Science Forum, 0, 645-648, 531-534.	0.3	2
132	(E)-1-(2-Iodophenyl)-2-phenyldiazene. Acta Crystallographica Section E: Structure Reports Online, 2011, 67, o2326-o2326.	0.2	2
133	Functionalization of suspended carbon nanotubes in silicon microsystems by Atomic Layer Deposition (ALD). , 2014, , .		2
134	Synthesis and Properties of Ethyl, Propyl, and Butyl Hexa-alkyldisilanes and Tetrakis(tri-alkylsilyl)silanes. Zeitschrift Fur Anorganische Und Allgemeine Chemie, 2014, 640, 2956-2961.	0.6	2
135	Atomic Layer Deposited Hybrid Organic-Inorganic Aluminates as Potential Low- κ Dielectric Materials. Materials Research Society Symposia Proceedings, 2015, 1791, 15-20.	0.1	2
136	Controllable template approach for ZnO nanowire growth. Physica Status Solidi (A) Applications and Materials Science, 2017, 214, 1600480.	0.8	2
137	Comparison of different coating techniques on the properties of FucoPol films. International Journal of Biological Macromolecules, 2017, 103, 268-274.	3.6	2
138	Phosphites as precursors in atomic layer deposition thin film synthesis. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2021, 39, 032404.	0.9	2
139	Influence of Annealing on the $\text{Al}_2\text{O}_3/\text{4H-SiC}$ Interface. Materials Science Forum, 2008, 600-603, 767-770.	0.3	1
140	Design of experiments approach to luminescent CaMoO_4 by atomic layer deposition. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2020, 38, 052408.	0.9	1
141	Selective etching of nanostructured a-Si:Al and its effect on porosity, Al gradient and surface oxidation. Thin Solid Films, 2020, 702, 137982.	0.8	1
142	Avoiding water reservoir effects in ALD of functional complex alkali oxides by using O_3 as the oxygen source. Dalton Transactions, 2022, 51, 927-934.	1.6	1
143	Photoactive Zr-aromatic hybrid thin films made by molecular layer deposition. RSC Advances, 2022, 12, 15718-15727.	1.7	1
144	Publisher's Note: ALD Applied to Conformal Coating of Nanoporous $\hat{\text{I}}^3$ -Alumina: Spinel Formation and Luminescence Induced by Europium Doping [<i>i></i>]. Electrochem. Soc. <i></i></i> , 159, P45 (2012)]. Journal of the Electrochemical Society, 2012, 159, S15-S15.	1.3	0

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145	(Tutorial) ALD Precursors and Processes for Alkali Metal-Containing Thin Films. ECS Meeting Abstracts, 2021, MA2021-02, 846-846.	0.0	0
146	Growth of nano-needles of manganese(IV) oxide by atomic layer deposition. Journal of Nanoscience and Nanotechnology, 2008, 8, 1003-11.	0.9	0
147	Investigation of the Atomic Layer Deposition of the Titanium Dioxide (TiO ₂) Film as pH Sensor Using a Switched Capacitor Amplifier. Chemosensors, 2022, 10, 274.	1.8	0